CLAIMS:

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What is claimed is:

1. An electro-static discharge device having connections to a pad and a substrate, said electro-static discharge device comprising:

a diode coupled for providing a bias signal, having a cathode coupled to said pad and an anode coupled to said substrate; and

a transistor operating in response to said bias signal, said transistor having a drain terminal coupled to said pad, a source terminal coupled to said substrate, and a gate terminal coupled to said substrate and to said source terminal.

- 2. The electro-static discharge device of claim 1, further comprising a substrate resistor having a first conduction terminal coupled to said gate terminal of said transistor and said source terminal of said transistor, and a second conduction terminal coupled to said substrate.
- 3. The electro-static discharge device of claim 1, wherein the substrate is coupled to receive a ground reference potential and comprises a material having a first conductivity type and a first doping concentration, and the anode of the diode comprises a material having the first conductivity type and a second doping concentration that is greater than the first doping concentration.
- 4. The electro-static discharge device of claim 3, wherein the drain of the transistor, the source of the transistor, and the cathode of the diode comprise a material with a second conductivity type that is opposite in polarity to the first conductivity type.
- 5. The electro-static discharge device of claim 1, wherein the diode comprises a MOS diode coupled for providing the bias signal to the gate terminal of the transistor in response to a pad voltage that is greater than an operating voltage.

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- 6. The electro-static discharge device of claim 1, wherein the diode comprises a zener diode coupled for providing a bias signal to the gate terminal of the transistor in response to a pad voltage that is greater than an operating voltage.
- 7. The electro-static discharge device of claim 1, wherein the transistor, operating in response to the bias signal from the diode, is coupled for conducting a current from the pad to the substrate.
 - 8. The electro-static discharge device of claim 1, wherein said transistor is a MOSFET.
- 9. A semiconductor device having a pad and a substrate, comprising:

a diode coupled for providing a bias signal, said diode having a first conduction terminal coupled to said pad and a second conduction terminal coupled to said substrate.

a transistor operating in response to said bias signal, said transistor having a first conduction terminal coupled to said pad, a second conduction terminal coupled to said substrate, and a control terminal coupled to said second conduction terminal and to said substrate.

- 10. The semiconductor device of claim 9, further comprises a substrate resistor having a first conduction terminal coupled to said control terminal of said transistor and said second conduction terminal of said transistor, and a second conduction terminal coupled to said substrate.
- 11. The semiconductor device of claim 9, wherein said transistor, operating in response to said bias signal from said diode, is coupled for conducting a current from said pad to said substrate.
- 12. The semiconductor device of claim 11, wherein said transistor comprises a Metal Oxide Semiconductor field effect transistor having a gate terminal coupled for receiving said bias signal.

said substrate; and

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- 13. The semiconductor device of claim 11, wherein said transistor is an N-type MOSFET.
- 14. The semiconductor device of claim 9, wherein said diode comprises a zener diode coupled for providing said bias signal to said control terminal of said transistor in response to a pad voltage that is greater than an operating voltage.
- 15. The semiconductor device of claim 9, wherein said diode comprises an MOS diode coupled for providing said bias signal to said control terminal of said transistor in response to a pad voltage that is greater than an operating voltage.
- 16. A semiconductor chip package comprising
 a semiconductor chip having a substrate thereof electrically tied to ground; and
 an electrical connector configured to carry a supply voltage to said semiconductor chip;
 wherein said semiconductor chip contains an electrostatic discharge device comprises
 a diode coupled for providing a bias signal, said diode having a first conduction
 terminal coupled to said electrical connector and a second conduction terminal coupled to

a transistor operating in response to said bias signal, said transistor having a first conduction terminal coupled to said electric connector, a second conduction terminal coupled to said substrate, and a control terminal coupled to said second conduction terminal and to said substrate.

17. A method of protecting a semiconductor device, comprising:

detecting a first signal that is greater than a second signal; and
conducting said first signal into a substrate that is coupled to receive a ground reference
potential upon detecting said first signal.

18. The method of claim 17, wherein detecting said first signal comprises: conducting a current of said first signal through a diode; and providing a control signal to a control terminal of a transistor in response to conducting said current.

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19. The method of claim 17, wherein conducting said first signal comprises:

receiving a control signal at a control terminal of a transistor; and

converting said first signal into a current with a substrate resistor that is coupled to the
substrate, thereby conducting the first signal into the substrate.

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20. A method of making an electrostatic discharge semiconductor device on a semiconductor substrate having a first conductivity type and a first doping concentration, comprising:

implanting into the substrate first, second, and third well regions having second conductivity types that are opposite in polarity to said first conductivity type;

implanting a fourth well region of the first conductivity type adjacent to said substrate and adjacent to said first well region; and

forming an insulated terminal across said second and said third well regions.

- 21. The method of claim 20, further comprising implanting a fifth well region into said substrate having the first conductivity type and a second doping concentration.
- 22. The method of claim 20, wherein implanting said fourth well comprises doping the fourth well region with a second doping concentration that is greater than the first doping concentration.
- 25 23. The method of claim 20, further comprising forming an insulated terminal above said first well region.

- 24. The method of claim 20, wherein said fourth well region comprises a halo region adjacent to said first well region that reduces a breakdown voltage between the first well region to the substrate.
- 5 25. The method of claim 20, wherein the fourth well region comprises forming a lightly doped drain adjacent to said first well region that reduces a breakdown voltage between said first well region to said substrate.
- 26. The method of claim 20, wherein said fourth well region is adjacent to said second well region that reduces a breakdown voltage between said first well region to said substrate.